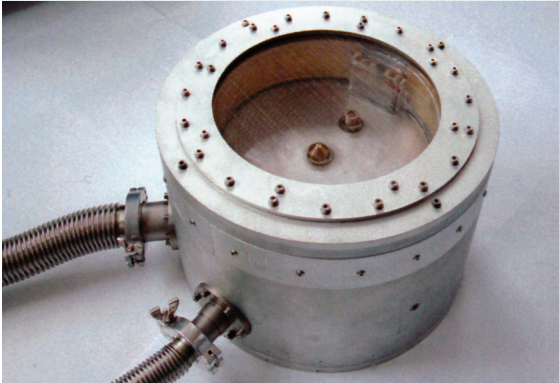


Taurion Source 300

Radio Frequency Plasma Source for Enhancement
to Existing PVD Coaters



Stand-alone RF Plasma Source enabling vacuum coaters to easily upgrade their existing PVD systems (chambers from 650 mm/25" to 110mm/43"). Based on the well established and proven Taurion Series RF-PEPVD technology, the Taurion Source 300 consists of an RF Plasma Source and stand-alone module containing laptop PC, control system, mass flow controller, power generator, and connection lines.



By upgrading your existing coater or replacing the current ion source the Taurion Source 300 enables the production of densified oxide layers (SiO_2 , TiO_2 , Ta_2O_5 , Nb_2O_5 , and more), shift free layers (filters), and nitrate lairs. Additionally, you can plasma etch, clean and degases substrate surfaces in free environment.

The Taurion Source 300 is very simple to integrate and operate, 400+ hours of operation without maintenance consisting of a cloth wipe down and possible extraction grid replacement, enables use of the basically neutral plasma generated from the high-frequency plasma source eliminating potential damage to the substrates by electrical discharges, and provides very high long term stability. Additionally, the use of pure process gasses (i.e. oxygen and argon) expands new areas of applications, where other processes are not suitable.

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